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(12) **United States Design Patent**  
**Morita et al.**

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(54) **SEPARATOR OF SUBSTRATE PROCESSING APPARATUS**

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(\*\*) Term: **15 Years**

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(30) **Foreign Application Priority Data**

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(51) **LOC (14) Cl.** ..... **13-03**

(52) **U.S. Cl.**  
USPC ..... **D13/182**

(58) **Field of Classification Search**  
USPC ..... D13/154, 173, 178, 182, 199; D24/127, D24/129  
CPC ..... H01L 21/67303; H01L 21/67306; H01L 21/67309; H01L 21/67126; H01L 21/67757; H01L 21/67748; H01L 21/683; H01L 21/68728; H01L 21/6875  
See application file for complete search history.

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(57) **CLAIM**

The ornamental design for a separator of substrate processing apparatus, as shown and described.

**DESCRIPTION**

FIG. 1 is a front, top and right side perspective view of a separator of substrate processing apparatus showing our new design;

FIG. 2 is a front elevational view thereof;

FIG. 3 is a rear elevational view thereof;

FIG. 4 is a right side elevational view thereof;

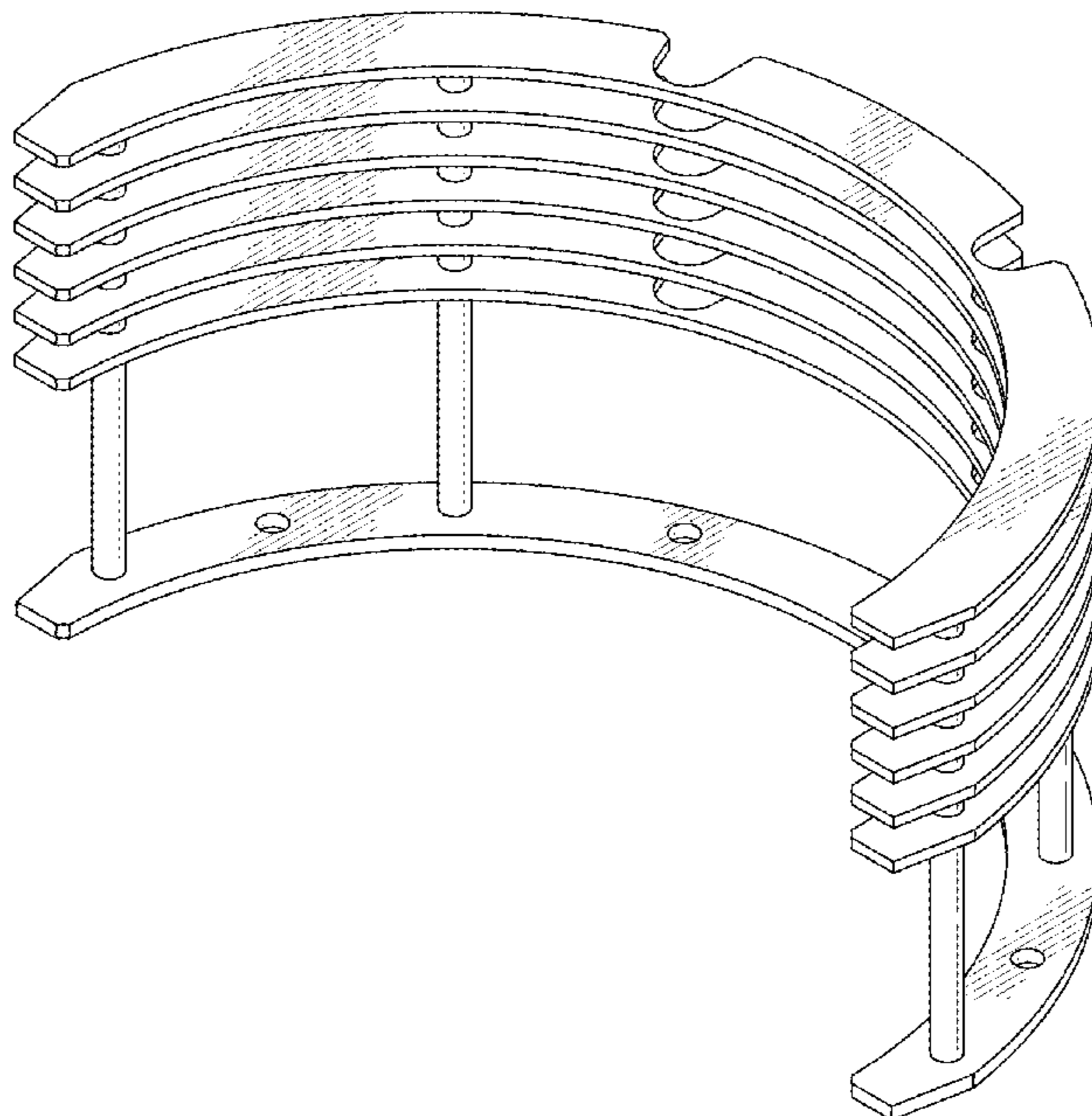
FIG. 5 is a left side elevational view thereof;

FIG. 6 is a top plan view thereof;

FIG. 7 is a bottom plan view thereof; and,

FIG. 8 is a cross sectional view taken along line 8-8 in FIG. 2.

**1 Claim, 5 Drawing Sheets**



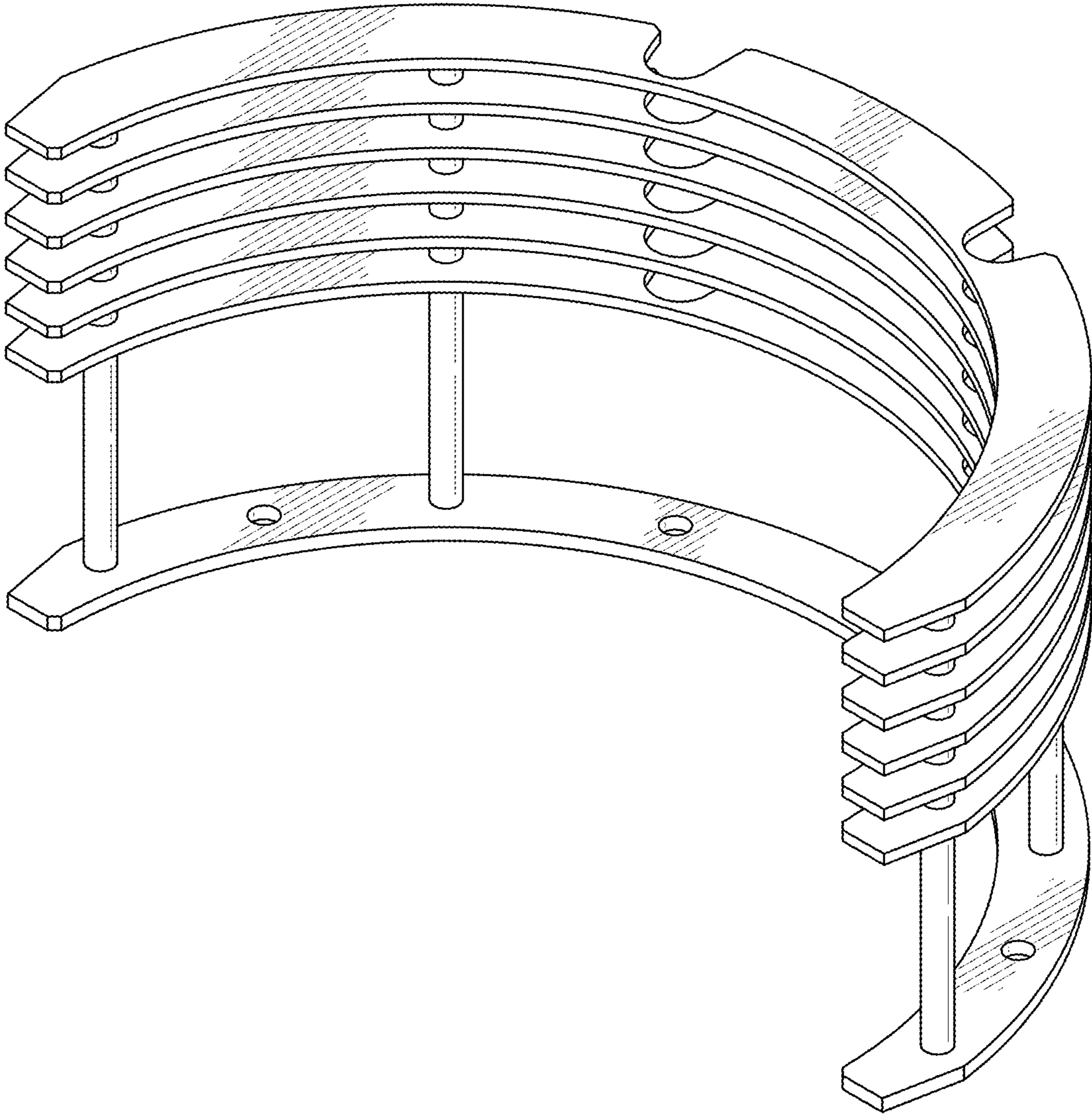
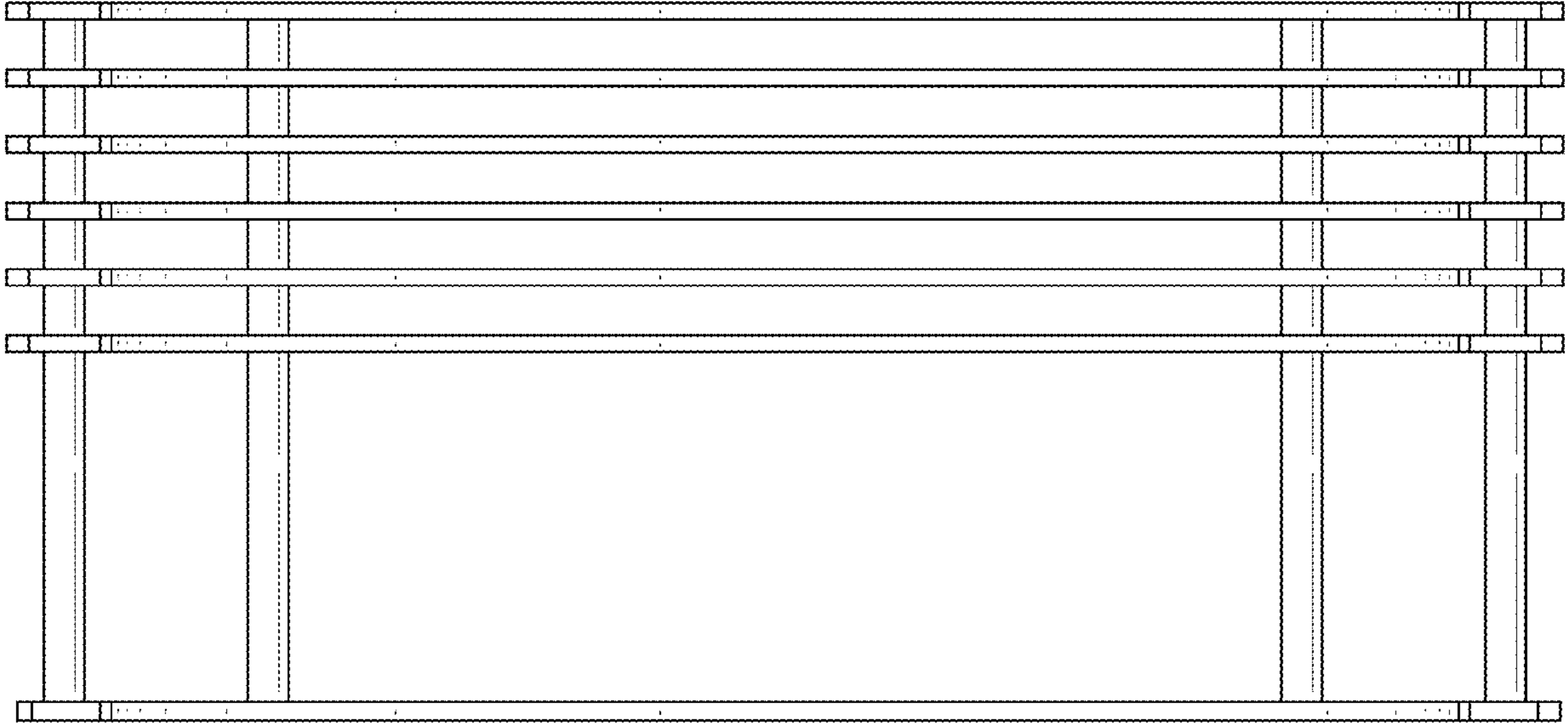


FIG. 1

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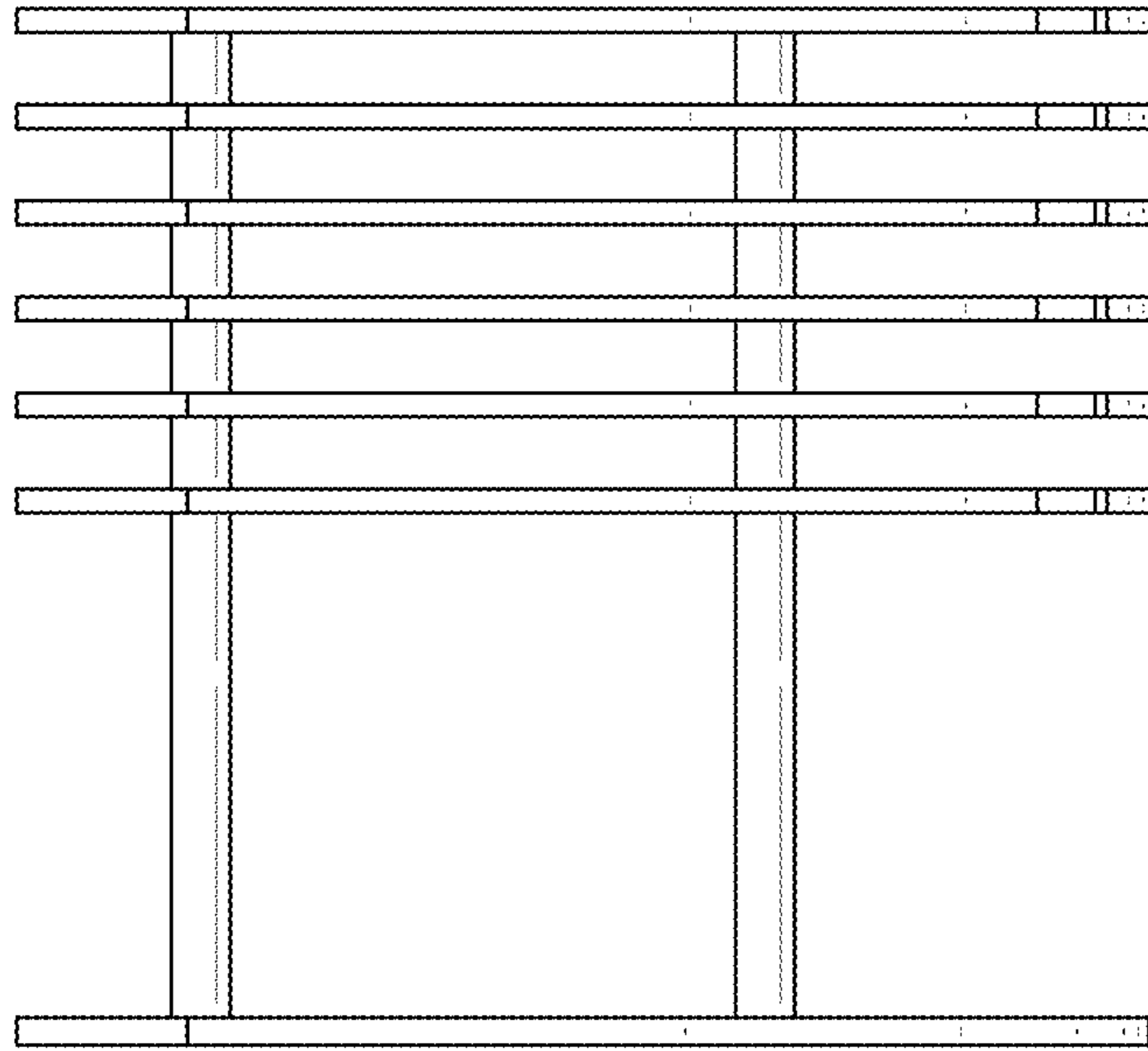


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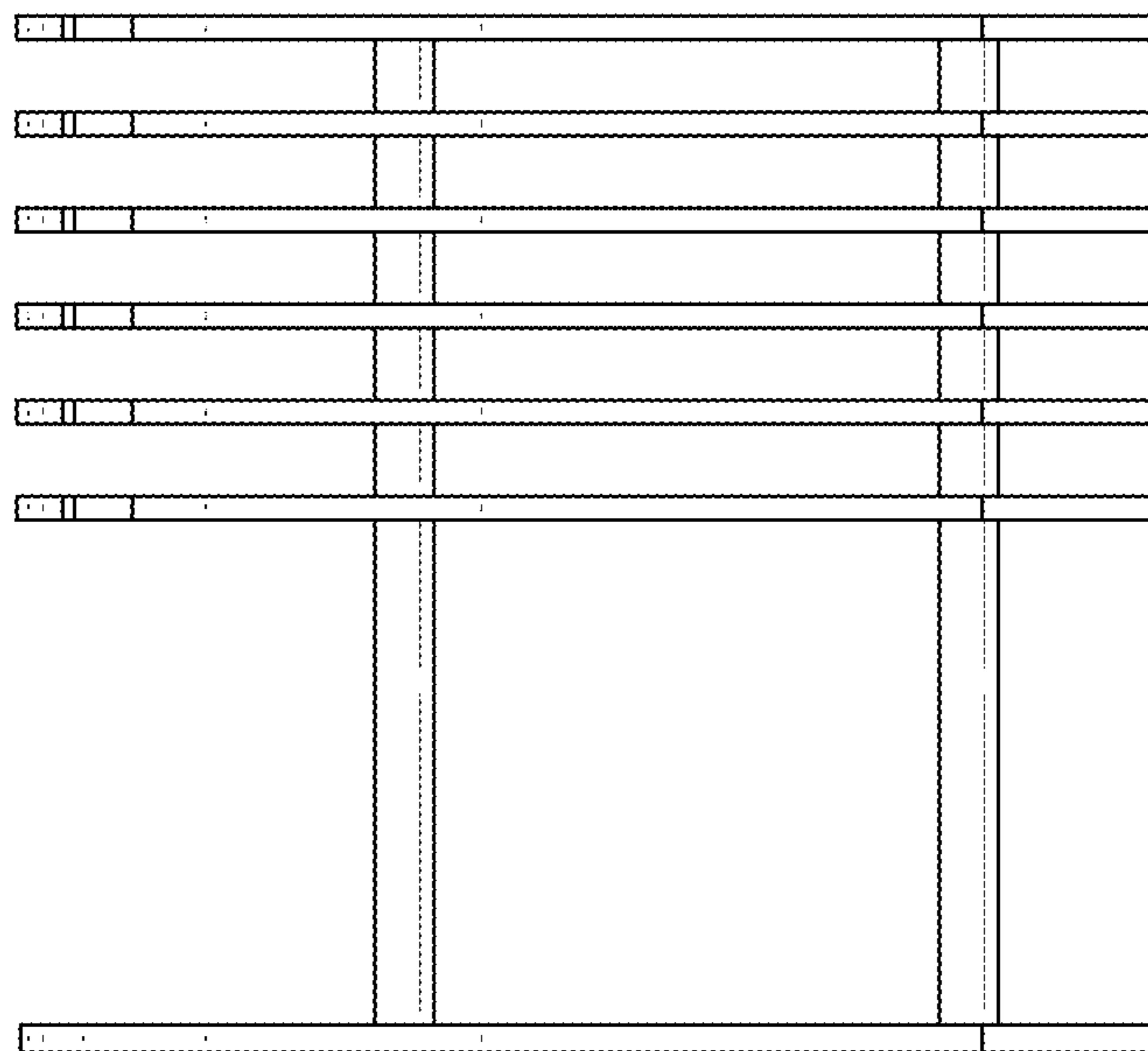
**FIG. 2**



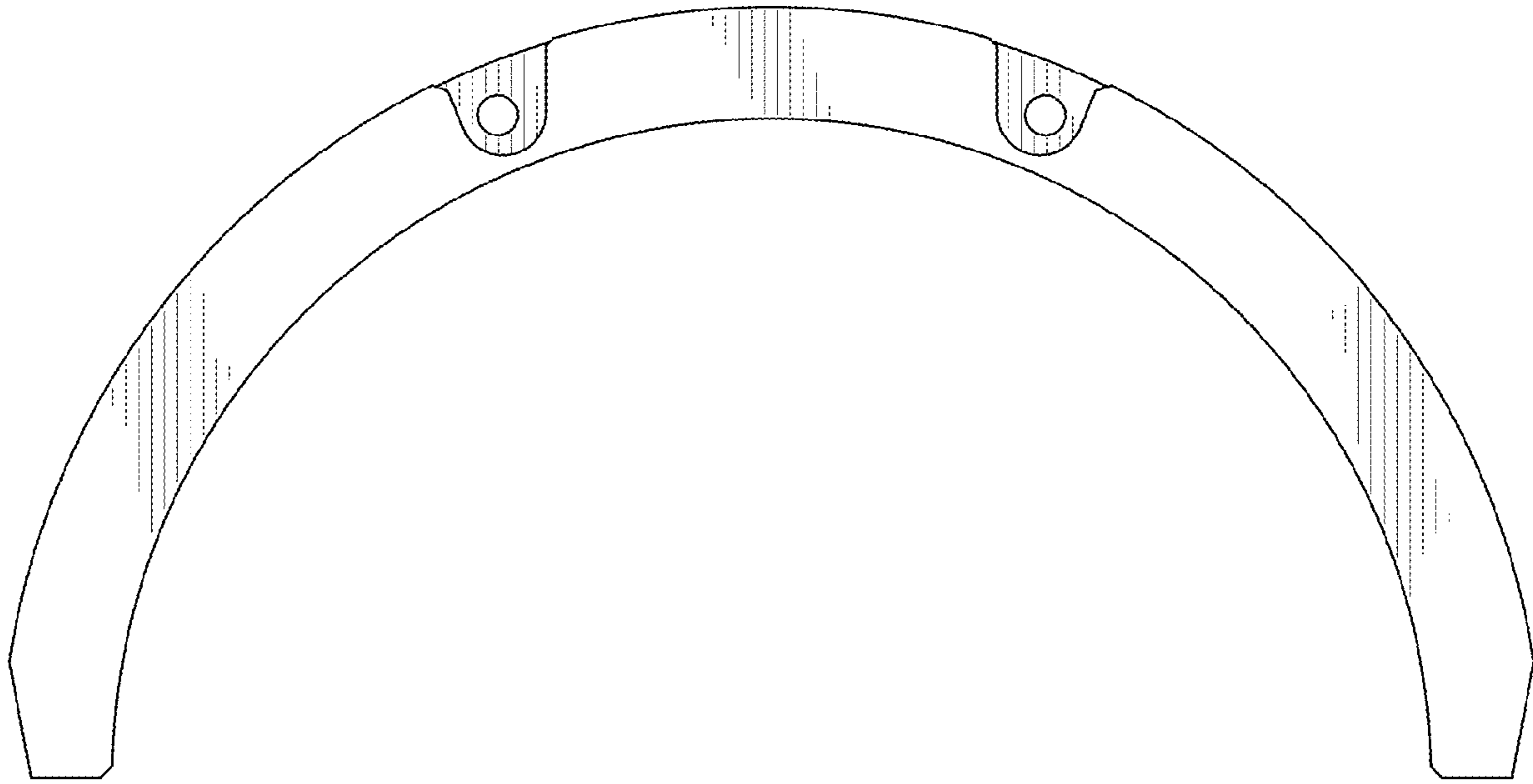
**FIG. 3**



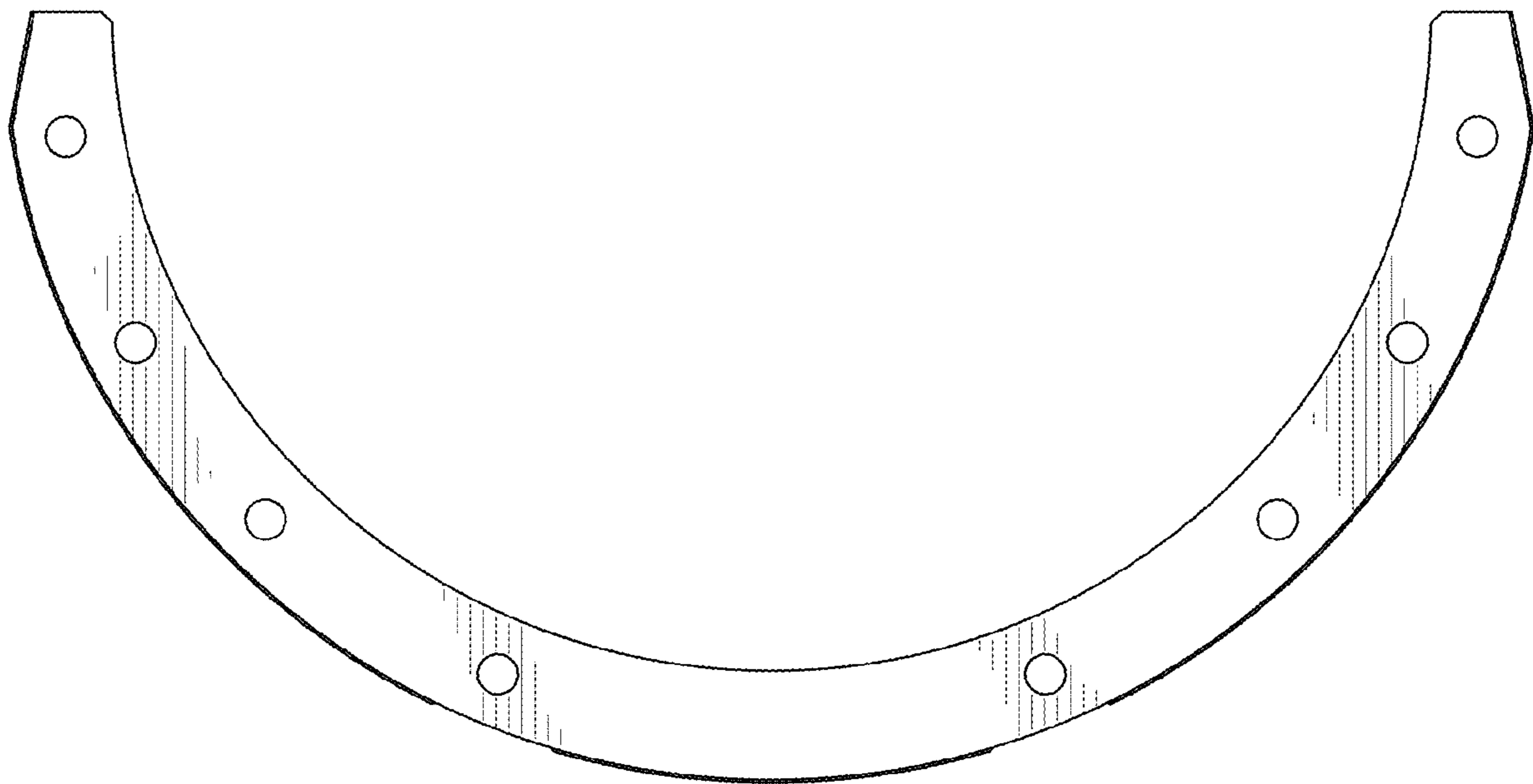
*FIG. 4*



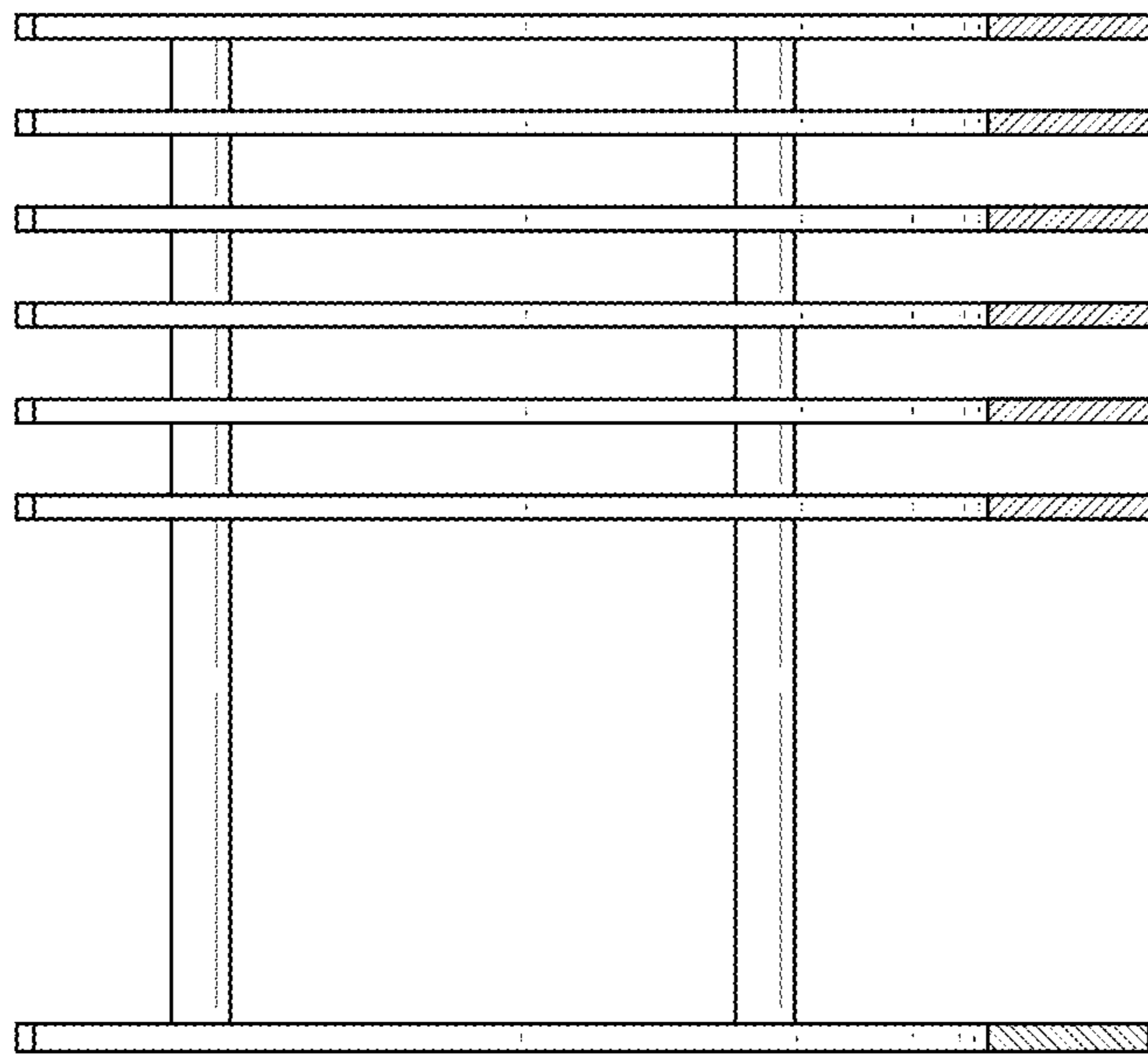
*FIG. 5*



*FIG. 6*



*FIG. 7*



*FIG. 8*